

## Japan TC Chapter of Automation Technology Global Technical Committee Meeting Summary and Minutes

Japan Standards Winter 2014 Meetings  
Tuesday, December 9, 2014, 1:30 p.m. – 5:00 p.m.  
SEMI Japan office, Tokyo, Japan

### Next Committee Meeting

Thursday, April 9, 2015, 2:00 p.m. – 3:30 p.m. <Japan Standard Time>  
Japan Standards Spring 2015 Meetings, Tokyo, Japan

### Committee Announcements (optional)

None

### Table 1 Meeting Attendees

*Italics indicates virtual participants*

**Co-Chairs:** Makoto Ishikawa (Nisshinbo Mechatronics), Ken Sambu (Mitsubishi Electric), Terry Asakawa (Tokyo Electron)

**SEMI Staff:** Chie Yanagisawa (SEMI Japan)

**Attendee:** 3 + **SEMI:** 1

<i>Company</i>	<i>Last</i>	<i>First</i>	<i>Company</i>	<i>Last</i>	<i>First</i>
Mitsubishi Electric	Sambu	Ken	Tokyo Electron	Murata	Naoko
Tokyo Electron	Asakawa	Terry	SEMI Japan	Yanagisawa	Chie

*\* alphabetical order by company name*

### Table 2 Leadership Changes

None

### Table 3 Ballot Results (or move to Section 4, Ballot Review)

None

### Table 4 Authorized Ballots (or move to Section 7, New Business)

None

### Table 5 Authorized Activities (or move to Section 7, New Business)

None

### Table 6 New Action Items (or move to Section 8, Action Item Review)

None

### Table 7 Open Actions Items (or move to Section 8, Action item Review)

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
20140729-2:	Japan members of Global EIS TF	To review the SNARF # 5222 => OPEN

## 1 Welcome, Reminders, and Introductions

Ken Sambu (Mitsubishi Electric), co-chair, called the meeting to order at 1:30 p.m. The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

## 2 Review of Previous Meeting Minutes

The committee reviewed the minutes of the previous meeting.

<b>Motion:</b>	To approve the previous meeting minutes written as it is.
<b>By / 2<sup>nd</sup>:</b>	Naoko Murata (Tokyo Electron) / Terry Asakawa (Tokyo Electron)
<b>Discussion:</b>	None
<b>Vote:</b>	2 in favor and 0 opposed. <b>Motion Passed.</b>

## 3 Technical Committee Award

The Japan TC Chapter of Automation Technology Global Technical Committee gave the Technical Committee Awards to Emi Ishikawa (Atelier Ishikawa) for her dedication to the Japan TC Chapter of PV Automation Global Technical Committee as a co-chair for about four years since the TC Chapter had been set up in 2010 to the TC transformed to Automation Technology TC in 2014.

## 4 Liaison Reports

### 4.1 *Europe TC Chapter*

Chie Yanagisawa (SEMI Japan) conveyed the message from Andrea Busch (SEMI Europe) that the European Automation Technology Committee could not meet at SEMICON Europa 2014 because there were not enough participants.

### 4.2 *SEMI Staff Report*

Chie Yanagisawa (SEMI Japan) gave the SEMI Staff Report. Of note:

- Global SEMI Events
- Global Standards Meetings Schedule
- SEMICON Japan Meeting Schedule
- Ballot Critical Dates
- New Regulations and Procedure guide
- Publication Update
- Contact Information

Attachment: [01\\_SEMI Staff Report 2014 December\\_R0.3a](#)

## 5 Ballot Review

None

## 6 Subcommittee & Task Force Reports

### 6.1 Equipment Interface Specification (EIS) Task Force

Ken Sambu reported for the EIS Task Force as attached.

Attachment: [02\\_EIS\\_141209a](#)

## 7 Old Business

### 7.1 Extending SNARF #5222

Ken Sambu addressed the committee on this topic.

<b>Motion:</b>	To extend SNARF #5222 by one year
<b>By / 2nd:</b>	Naoko Murata (Tokyo Electron) / Terry Asakawa (Tokyo Electron)
<b>Discussion:</b>	None
<b>Vote:</b>	2 in favor and 0 opposed. Motion passed.

## 8 New Business

### 8.1 Future activity of Automation Technology Committee

Terry Asakawa addressed the committee on this topic.

The TC Chapter discussed future activity from the viewpoint of the modeling of flow oriented manufacturing line. In most of the cases, factory control is modeled as data handling in a tiered information & control system, however, Automation Technology Committee to focus more on simultaneous material-information handling in object oriented manner.

## 9 Action Item Review

### 9.1 *Open Action Items*

Chie Yanagisawa (SEMI Japan) reviewed the open action item. This can be found in the Open Action Items table at the beginning of these minutes.

### 9.2 *New Action Items*

None

## 10 Next Meeting and Adjournment

The next meeting of the Japan TC Chapter of Automation Technology Global Technical Committee is scheduled for 2:00 p.m. – 3:30 p.m., XXXXX, XXXX X, 2015 at Japan Standards Spring 2015 Meetings at SEMI Japan office in Tokyo.

Staff will coordinate the next meeting as soon as possible after this meeting. (J. Collins)

3:40PM

Respectfully submitted by:  
Chie Yanagisawa  
Senior Standard Coordinator  
SEMI Japan  
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Minutes approved by:

<Name> (<Company>), Co-chair	<Date approved>
<Name> (<Company>), Co-chair	<Date approved>

**Table 8 Index of Available Attachments #1**

#	<i>Title</i>	#	<i>Title</i>
01	SEMI Staff Report 2014 December_R0.3a	02	EIS_141209a

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at [www.semi.org](http://www.semi.org). For additional information or to obtain individual attachments, please contact [SEMI Staff Name] at the contact information above.